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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): ENDOU et al.	Atty. Dkt.: 01-617
Serial No.: 10/824,497	Group Art Unit: 2812
Filed: April 15, 2004	Examiner: Unknown
Title: METHOD OF MANUFACTURING SILICON CARBIDE SEMICONDUCTOR DEVICE	

Commissioner for Patents
Alexandria, VA 22314

Date: May 5, 2005

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, the references listed on the attached Form PTO-1449 are being brought to the attention of the Examiner without any admission that they constitute statutory prior art, or without any admission that they contain subject matter that anticipates the invention or renders the invention obvious to a person of ordinary skill in the art.


Although no fees are believed to be due at this time, it is respectfully requested that any such fees be charged to Deposit Account 50-1147. Also, the Examiner is requested to initial the attached PTO Form-1449 and to return a copy of same to the undersigned attorney as proof that the listed references have been considered and made of record.

Respectfully submitted,



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FORM PTO-1449		ATTY. DKT NO. 01-617	SER. NO. 10/824,497
		APPLICANT ENDOU et al.	
		FILING DATE April 15, 2004	GROUP 2812

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS

FOREIGN PATENT DOCUMENTS

TRANSLATION

		DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO	
										Eng. Abstract
		WO 01/84609	11/8/01	PCT						

* Full English text is available in machine-translated form in JPO (Japanese Patent Office) English language web site at <http://www1.ipdl.jpo.go.jp/PA1/cgi-bin/PA1INDEX>.

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER	DATE CONSIDERED	